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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/824,428 04/15/2004		James F. Buller	50432-702	6497
7:	7590 11/10/2004		EXAMINER	
McDermott, Will & Emery 600 13th Street, N.W. Washington, DC 20005-3096			VU, DAVID	
			ART UNIT	PAPER NUMBER
			2818	

DATE MAILED: 11/10/2004

Please find below and/or attached an Office communication concerning this application or proceeding.

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	Application No.	Applicant(s)			
	10/824,428	BULLER ET AL.			
Office Action Summary	Examiner	Art Unit			
	DAVID VU	2818			
The MAILING DATE of this communication app Period for Reply	ears on the cover sheet with the c	orrespondence address			
A SHORTENED STATUTORY PERIOD FOR REPLY THE MAILING DATE OF THIS COMMUNICATION. - Extensions of time may be available under the provisions of 37 CFR 1.13 after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a reply If NO period for reply is specified above, the maximum statutory period w - Failure to reply within the set or extended period for reply will, by statute, Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	6(a). In no event, however, may a reply be time within the statutory minimum of thirty (30) days ill apply and will expire SIX (6) MONTHS from cause the application to become ABANDONE	nely filed s will be considered timely. the mailing date of this communication. D (35 U.S.C. § 133).			
Status					
 1) Responsive to communication(s) filed on 15 Oc 2a) This action is FINAL. 2b) This 3) Since this application is in condition for alloward closed in accordance with the practice under E 	action is non-final. ace except for formal matters, pro				
Disposition of Claims					
4) ☐ Claim(s) 10-12 and 16-19 is/are pending in the 4a) Of the above claim(s) is/are withdraw 5) ☐ Claim(s) is/are allowed. 6) ☐ Claim(s) 10-12 and 16-19 is/are rejected. 7) ☐ Claim(s) is/are objected to. 8) ☐ Claim(s) are subject to restriction and/or Application Papers 9) ☐ The specification is objected to by the Examine	vn from consideration. election requirement.				
· · · · · · · · · · · · · · · · · · ·	10)⊠ The drawing(s) filed on <u>04/15/04</u> is/are: a)⊠ accepted or b)□ objected to by the Examiner.				
	Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).				
	Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d). 1) The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.				
Priority under 35 U.S.C. § 119					
 12) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f). a) All b) Some * c) None of: 1. Certified copies of the priority documents have been received. 2. Certified copies of the priority documents have been received in Application No. 3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)). * See the attached detailed Office action for a list of the certified copies not received. 					
Attachment(s) Notice of References Cited (PTO-892) Notice of Draftsperson's Patent Drawing Review (PTO-948) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08) Paper No(s)/Mail Date 04/15/04.	4) Interview Summary Paper No(s)/Mail Da 5) Notice of Informal P 6) Other:				

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DETAILED ACTION

Claim Rejections - 35 USC § 102

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

(e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.

1. Claims 10-12, 15-16 and 19 are rejected under 35 U.S.C. 102(e) as being anticipated by Yu (US 6,506,650).

Regarding claims 10-12,16 and 19, Yu in related text (Col. 3, Lines 7-39 and Col. 4, Lines 15-21) and figures (Figs. 1-4) discloses a method for fabricating a semiconductor device, comprising: forming a gate electrode 16 over a substrate 12 with a gate dielectric layer 20 therebetween; forming an oxide liner 26 on the side surfaces of the gate electrode 16 and the upper surface of the substrate 12; forming a nitride liner 28 on the oxide liner 26 and forming an oxide sidewall spacer 32 (k<3.9) on the nitride liner 28; ion implantation to form shallow source /drain extensions 22 at a junction depth of about 100-250Å in the upper surface of the substrate 12, using the gate electrode 16 as a mask, before forming the composite liner.

2. Claims 10-12 and 16-18 are rejected under 35 U.S.C. 102(e) as being anticipated by Miles (US 6,235,597).

Regarding claims 1-8,10-12 and 16-19, Miles in related text (Col. 2, Line 51-Col. 3, Line 27 and Col. 3, Lines 60-62) and figure (Fig. 1) discloses a method for fabricating a semiconductor device, comprising: forming a gate electrode 3 over a substrate 1 with a gate dielectric layer 2 therebetween; forming an oxide liner 4 on the side surfaces of the gate electrode 3 and the upper surface of the substrate 1; forming a nitride liner 5 on the oxide liner 4 and forming an oxide sidewall spacer 6 on the nitride liner 5; ion implantation to form shallow source /drain extensions 10 at a junction depth of about 0.1µm by using p-type dopants such as boron in the upper surface of the substrate 1, using the gate electrode 3 as a mask, before forming the composite liner.

Conclusion

3. Any inquiry concerning this communication or earlier communications from the examiner should be directed to David Vu whose telephone number is (571) 272-1798. The examiner can normally be reached on Monday-Friday from 8:00am to 5:00pm. If attempt to reach the examiner by telephone are unsuccessful, the examiner's supervisor, David Nelms can be reached on (571) 272-1787. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent

Application Information Retrieval (PAIR) system. Status information for published applications

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may be obtained from either Private PAIR or Public PAIR, Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR

system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR

system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

David Vu

Shuland

November 06, 2004.